

<b>Notice of References Cited</b>	Application/Control No. 10/655,581	Applicant(s)/Patent Under Reexamination TWITCHEN ET AL.	
	Examiner Stuart Hendrickson	Art Unit 1754	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,328,548	07-1994	Tsuji et al.	117/79
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Yan et al., 'Very high Growth Rate Chemical Vapor Deposition of Single-Crystal Diamond' in Proceedings of the Nat'l Academy of Sciences vol. 99 no. 20 pgs. 12523-12525 10/1/02.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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